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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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TITLE: ELECTRON BEAM IRRADIATION DEVICE

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AMENDED ABSTRACT

In an An electron beam irradiation device comprising: having an electron beam generating unit R, an irradiation chamber E for irradiating an electron beam to a irradiated object F, and an oxygen cutoff section S for blowing inert gas N on an upstream side of the irradiated chamber, the. The oxygen cutoff section is designed so that a gap Ws between partitions across the irradiated object is smaller than a gap We between the partitions across the irradiated object in the irradiation chamber ($W_s < W_e$), the. The gap Ws is made uniform, or almost uniform, throughout the entire area of the oxygen cutoff section, and a blowing slit S5 for blowing the inert gas to the processing surface of the irradiated object is provided on a partition with no projection nor recess involved.